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Step 1

2D PtSe<sub>2</sub> is continuing to attract considerable research interest due to its semi-metallic to semiconducting transition at reduced thicknesses [1,2]. Here, we present method for conformal and selective deposition of PtSe<sub>2</sub> at back end of line compatible temperatures, enabling new fabrication routes through controlled patterned synthesis [3].

Platinum deposited by area selective atomic layer deposition is converted to PtSe<sub>2</sub> via thermal assisted conversion (Figure 1) [4]. The growth is described for a variety substrates and morphologies, including conformally on 3D topography, and is characterized by Raman, spatially resolved X-ray photoelectron spectroscopy, scanning and tunnelling electron microscopy. Furthermore, the fabrication of a 3D highly sensitive ammonia sensor and a fully integrated infrared-photodetector on silicon photonic waveguides demonstrate the versatility of this approach.

## References

[1] L. Zeng et. al, NPG Asia Mater 10 (2018) 352–362.

- [2] L. Ansari et. al., npj 2D Mater Appl 3 (2019) 1-8.
- [3] M. Prechtl et. al, Adv Funct Materials 31 (2021) 2103936.
- [4] C. Yim et. al, ACS nano 10 (2016) 9550–9558.



Step 3

**Figure 1:** Process flow for selective and conformal deposition of PtSe<sub>2</sub>. Al<sub>2</sub>O<sub>3</sub> deposited by atomic layer deposition on silicon photonic waveguide structures is patterned using electron beam lithgraphy (Step 1). After buffered hydrofluoric acid (BHF) etching using the resist as hard mask (Step 2) Pt is selectively and conformally deposited (Step 3) and finally converted to PtSe<sub>2</sub> (Step 4).

Step 2



**Figure 2:** Left: Schematic of a fully integrated IR-photodetector using selectively and conformally deposited PtSe<sub>2</sub> as the active sensing material. Right: Time resolved photoresponse under pulsed excitation.

Step 4